

A Silicon-Tungsten ECal with Integrated Electronics

R. Frey¹, J. Brau¹, M. Breidenbach², D. Freytag², G. Haller², R. Herbst², R. Lander³,
T. Nelson², V. Radeka⁴, D. Strom¹, and M. Tripathi³ *

1- University of Oregon - Dept of Physics and Center for High Energy Physics
Eugene, Oregon - USA

2- Stanford Linear Accelerator Center
Stanford, California - USA

3- University of California - Dept of Physics
Davis, California - USA

4- Brookhaven National Laboratory - Physics Division
Upton, New York - USA

We summarize recent R&D progress for a silicon-tungsten electromagnetic calorimeter (ECal) with integrated electronics, designed to meet the ILC physics requirements.

1 Overview

A basic physics requirement for ILC detectors is that they provide excellent reconstruction of hadronic final states. This allows access to new physics which is complementary to the LHC. One statement for a requirement on jet reconstruction is that intermediate particles which decay into jets, such as W, Z, or top, can be identified and isolated. This places unprecedented requirements on 2-jet or 3-jet mass resolution, typically at the level of 3-5% using the PFA technique, which makes challenging demands on the calorimeters. The electromagnetic energy resolution is not expected to limit jet resolution using a PFA. However, particle separation—photon-photon and charged hadron-photon—is crucial. In addition, if one provides this kind of imaging calorimeter to meet the PFA needs, these same features will also be put to good use for reconstruction of specific tau decay modes (to enable final-state polarization measurement), to “track” photons (even if originating from a vertex displaced from the interaction point), to track MIPS, and so forth. Figure 1 and Table 1 provide some context for our ECal design within the SiD detector concept, along with some main design parameters. More detail is included in the presentation[1].

inner radius of ECal barrel	1.27 m
maximum z of barrel	1.7 m
longitudinal profile	(20 layers \times 0.64 X_0) + (10 layers \times 1.3 X_0)
silicon sensor segmentation	1024 hexagonal pixels
pixel size	13 mm ²
readout gap	1 mm (includes 0.32 mm silicon thickness)
effective Moliere radius	13 mm
pixels per readout chip	1024

Table 1: Main parameters of the silicon-tungsten ECal for SiD.

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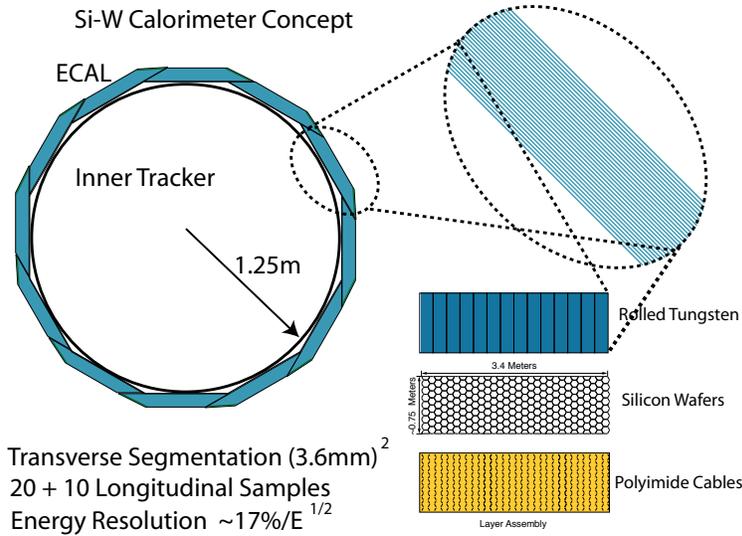


Figure 1: Silicon-tungsten ECal as envisioned for the SiD concept.

The thrust of our R&D project is to integrate detector pixels on a large, commercially feasible silicon wafer, with the complete readout electronics, including digitization, contained in a single chip (the *KPiX* ASIC) which is bump bonded to the wafer. We take advantage of the low beam-crossing duty cycle (10^{-3}) to reduce the heat load using power cycling, thus allowing passive-only thermal management. Our design then has several important features: The electronics channel count is effectively reduced by a factor of 1024; the transverse segmentation down to a few mm can be naturally accommodated (with the cost, to first order, not dependent on the segmentation choice); the readout gaps can be small (1 mm). This last property is crucial for maintaining the small Moliere radius intrinsic to tungsten.

2 Sensor and electronics progress

Based on the lab measurements[2] performed on the version 1 silicon sensor prototypes, we have developed a design for new (version 2) sensors which can be used to fabricate a full-depth (30-layer) ECal module. The new sensor design is depicted in Fig. 2. The layout minimizes capacitive and resistive noise contributions from the signal traces, especially in the vicinity of the *KPiX* chip. A typical trace contributes $C \sim 20$ pF and $R \sim 300 \Omega$.

The readout of the Si pixels must accommodate a very large dynamic range. Based on EGS4 simulations, the largest signals in a single pixel—arising from 500 GeV Bhabha electrons—correspond to about 2000 MIPs at shower max. At the low end, one requires measuring MIPs well above the electronic noise ($\text{SNR} \approx 7$ or better). The *KPiX* design incorporates this large dynamic range in a novel way, using on-the-fly range switching. Figure 3 shows this range-switching function in action in the lab. In the plot, as the injected charge is increased, we see the range switch at about 700 fC. For 320 micron silicon, 1 MIP

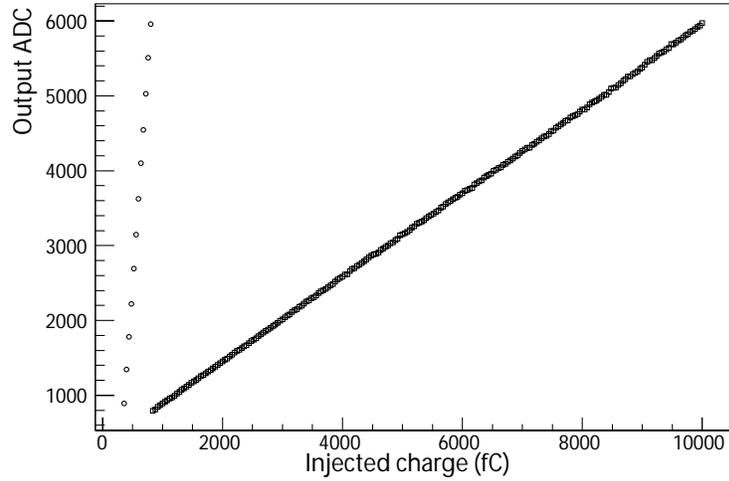


Figure 3: KPiX output as a function of input charge, showing the dynamic gain change at about 700 fC.

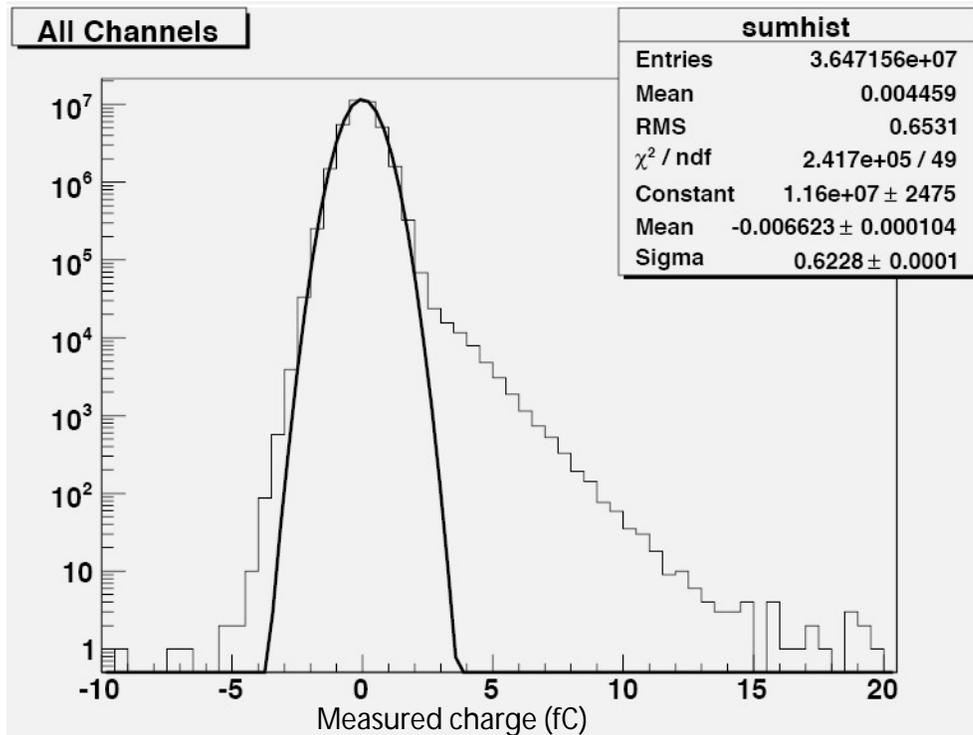


Figure 4: Distribution of charge collected by the KPiX v4 chip at the SLAC ESA.